

INTERLOCK APPARATUS AND METHOD FOR SUPPLYING GAS TO A
SEMICONDUCTOR MANUFACTURING DEVICE

ABSTRACT OF THE DISCLOSURE

5 A gas supplying apparatus for a semiconductor manufacturing device has an interlock
apparatus that includes at least one solenoid valve that controls the gas supply from a gas
source to the semiconductor manufacturing device, a main controller configured to output a
control signal for the semiconductor manufacturing device and a driver signal, a driver
configured to apply a driving voltage to the at least one solenoid valve in response to the
10 driver signal, and an interlocker configured to sense the open/shut state of the solenoid valves
and configured to transmit an interlock signal to the main controller.